

In re Application of:

Lawrence C. Lei

Serial No.: 10/792,323

Confirmation No.: 4370

Filed: March 3, 2004

For: Apparatus and Method for Vaporizing Solid Precursor for CVD or Atomic Layer Deposition

Group Art Unit: 3742

Examiner: Sang Y. Paik

MAIL STOP AF

## Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

## CERTIFICATE OF TRANSMISSION

I hereby certify that this correspondence is being electronically transmitted to the U.S. Patent and Trademark Office via EFS-Web to the attention of Examiner Sang Y. Palk, on the date shown below.

May 21, 2008

Date \_\_\_\_\_

John-Paul F. Cherny

Dear Sir:

**RESPONSE TO FINAL OFFICE ACTION DATED FEBRUARY 21, 2008**

In response to the Final Office Action dated February 21, 2008, having a shortened statutory period for response set to expire on May 21, 2008, please enter this Response and reconsider the claims pending in the application for reasons discussed below. Although the Applicant believes that no additional fees are due in connection with this Response, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/APPM/005191.C1/JPC, for any fees, including extension of time fees or excess claim fees, required to make this Response timely and acceptable to the Office.

**Pending Claims** begin on page 2 of this paper. **Remarks** begin on page 4 of this paper.